

Datasheet: MakroPorP4.2S2.5-150

Macroporous silicon dead end pores (430927-W05)

Etching

pitch:	4.2 μm
pore length:	154 μm
pore diameter:	2-2.5 μm

Postprocessing

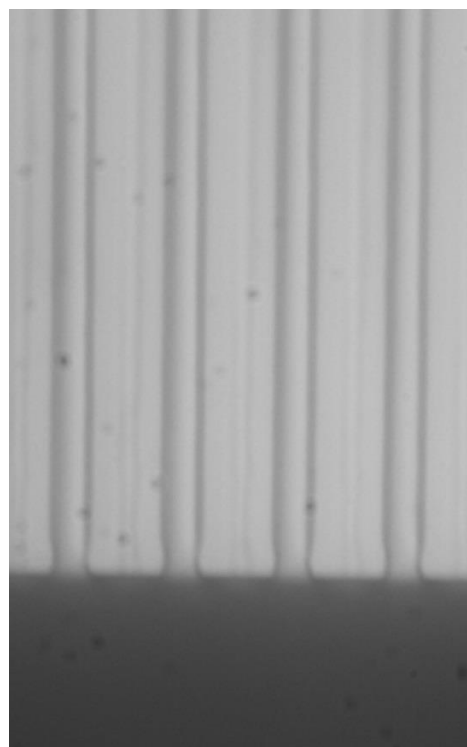
laser dicing

Images

Sideview, pore profile



Sideview, pore profile



Please note: The wafer surface is pre-structured with pyramidal pits prior to the photoelectrochemical pore formation process. Thus, optical microscopy from the front side does not show the real pore diameter.)